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PATENT & TRADEMARK OFFICE

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of:

Im-soo PARK, et al.	Art Unit: 1746
Serial No.: 10/685,515	Examiner: Saeed T. Chaudhry
Filed: October 16, 2003	*Confirmation No.: 8169*
For: APPARATUS FOR CLEANING SEMICONDUCTOR WAFER INCLUDING HEATING USING A LIGHT SOURCE AND METHOD FOR CLEANING WAFER USING THE SAME (AS AMENDED)	Attorney Docket No.: 249/255 DIV

AMENDMENT UNDER 37 C.F.R. § 1.114

Mail Stop: **RCE**
Commissioner for Patents
United States Patent and Trademark Office
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

INTRODUCTORY COMMENTS

In response to the Office Action Made Final mailed on October 30, 2006 and the Advisory Action mailed on February 2, 2007, and further to the Request for Continued Examination (RCE) and Petition for Extension of Time concurrently filed herewith, the following amendments and remarks are respectfully submitted in connection with the above-identified application:

Amendments to the Claims are reflected in a listing of claims, which begins on page 2 of this paper; and

Remarks begin on page 5 of this paper.

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